FEMTika

new

NEXT-GEN GLASS MICROPROCESSING WORKSTATION

Simple to operate

Budget friendly

Launching this June in LWOP Munich

FEATURES

- Multi-scale glass processing: achieve precision from μm to cm scales, ideal for advanced glass applications
- Autofocus
- Self-aligning optical system for reduced maintenance requirements
- High-sensitivity camera for real-time process monitoring
- Dual-objective head for effortless fabrication mode transition

INDUSTRIES

- Microrobotics
- Watch & Jewelry
- Photonics
- Industrial R&D
- Biotechnologies and Life science
- Medical
- Quantum computing

APPLICATIONS

- Micromechanical parts and assemblies from glass
- Microoptics, microlens arrays
- Micro-fluidics, LAB-ON-CHIP

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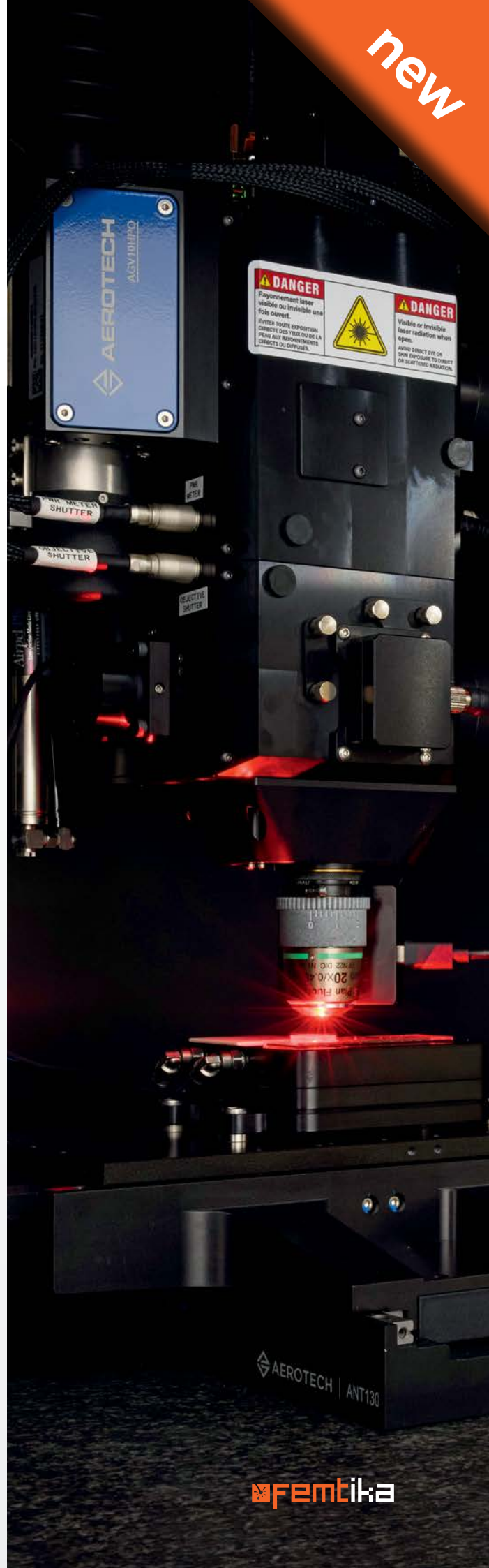
TECHNICAL SPECIFICATIONS

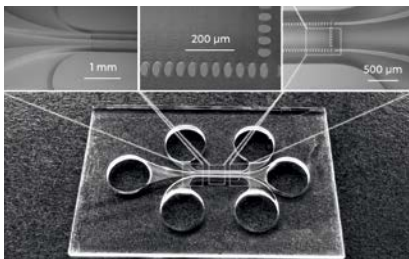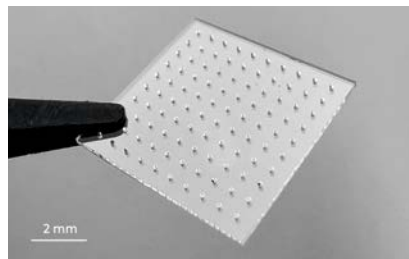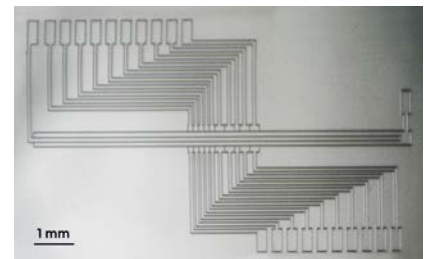|		
Femtosecond laser source	Central wavelength	1030 ± 10 nm
	Average power	10 W
	Max. pulse energy	> 100 uJ
	Repetition rate	100 kHz – 1 MHz
	Pulse duration	400 fs – 4 ps
Positioning stages (XYZ)	Travel (XYZ)	120 mm × 120 mm × 60 mm
	Accuracy	± 0.5 µm
	Bi-Directional Repeatability	± 0.15 µm
	Maximum speed (XY no load)	350 mm/s
Galvano scanners	Scan angle	± 0.35 rad
	Repeatability	0.4 µrad RMS
Process specifications	Technology	Selective laser etching, ablation, welding, refractive index modification
	Materials	Fussed silica, borosilicate glass and other transparent materials
	Smallest feature size	> 1 µm
	Minimum surface roughness	< 200 nm
	Maximum object height	20 mm
	Aspect ratio	> 1 : 200
	Minimum micro hole diameter	5 µm

PROCESSING CAPABILITTIES

Gears system

3D nozzle
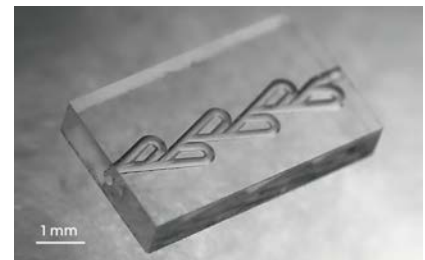
Tesla valve

Microfluidics

Quantum computing / TGV

Ion traps

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